

# GaAsSb/AlGaAsP Superlattice Polarized Electron Source

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Collaborator: DoE Jefferson Lab

DoE SBIR/STTR Exchange Meeting  
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# SVT Associates Company Overview

Founded in 1993 as Molecular Beam Epitaxy (MBE) equipment provider

- Originated from Perkin Elmer Physical Electronics MBE Group
- One of today's leading MBE suppliers by continual product development
- Over 160 MBE systems now in the field
- Strong UHV hardware, epitaxial growth, and thin film expertise
- Technology Driven Company
  - >30% employees are PhD scientists (currently 30 employees total)
  - Key engineers > 25 years experience in MBE and UHV technology
- Diverse system product line spanning Molecular Beam Epitaxy (MBE), Thin Film Deposition (i.e. ALD, PVD, PLD and Solar), and In-situ Thin Film Monitoring
- Only MBE Company with System, Components, Process, In-situ Monitoring Expertise with our own Applications Laboratory and Characterization Facility



# SVT Facilities and Capabilities

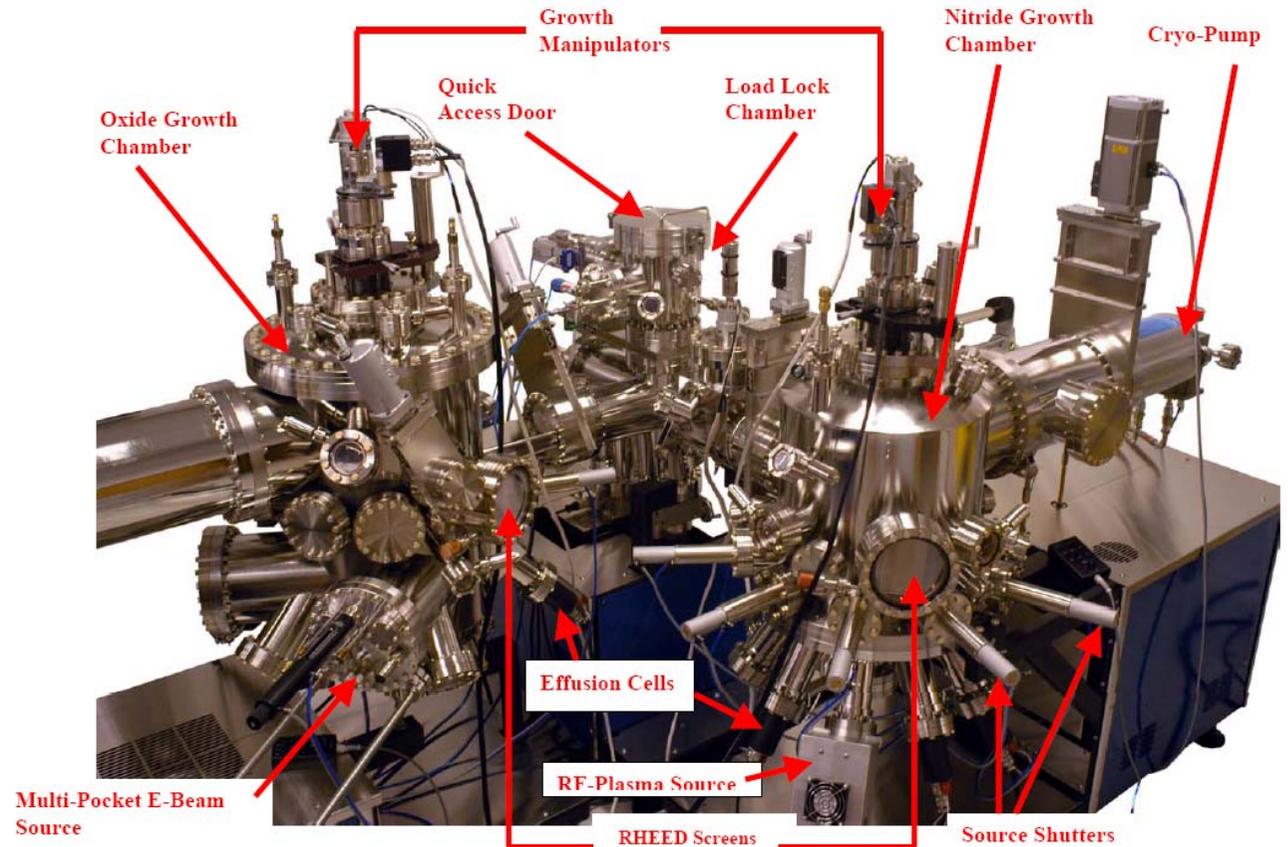
- Material deposition systems: MBE  
PLD, ALD

Established know-how:  
8 Applications Laboratory MBE  
systems producing world class  
epitaxial growth, feeding  
requirements back to equipment  
designers

- Complete semiconductor  
material characterization facility:  
HR-XRD, FTIR, Hall, Low-temp  
probe station, Semiconductor  
parameter analyzer,  
ellipsometer.

- Device Fabrication

Class-100 clean room, ICP dry  
etcher.



Dual Oxide - Nitride MBE



# Semiconductors Research at SVT

- US government, industrial research grants, and internal programs
- Established research collaboration with many universities: Illinois, North Carolina State, Florida, Stanford ...
- Highly technically oriented, PhD scientists & engineers
- > 100 book chapters, publications and presentations
- Significant Antimonide, Nitride and ZnO accomplishments
  - High power HEMT & MOSHEMT
  - Commercialized solar blind UV detector products
  - High efficiency photocathode
  - Innovative LED utilizing Quantum Structures
  - New mid Infrared Laser and Photodiode
  - Rainbow colored MgZnCdO



# Program Overview

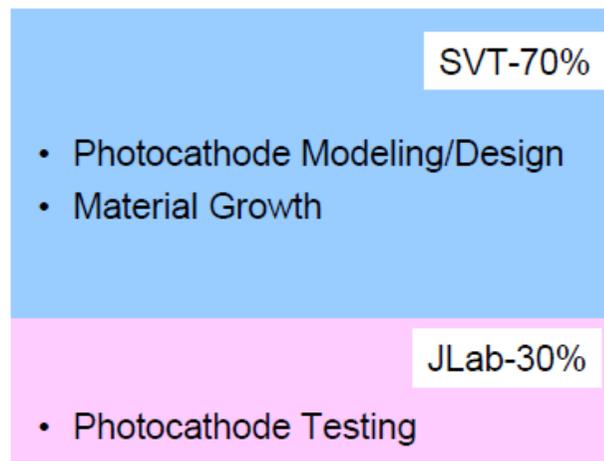
**Program title: GaAsSb/AlGaAsP Superlattice High-Polarization Electron Source**

## Ultimate goal:

cw polarized electron sources with >80% polarization and >10 mA beam current

## Present Applications:

- DoE needs: high energy accelerators
- Spintronics



## Potential Applications:

- Surface analysis
- Quantum computing
- Magnetic imaging

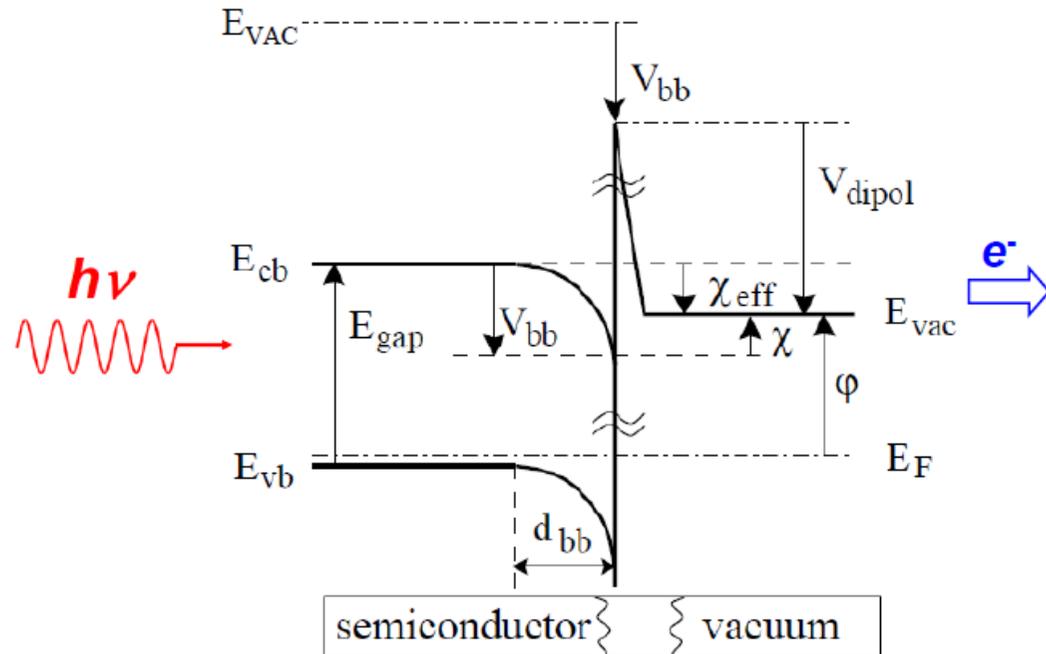


# Photocathode - General Properties

Photons → free electrons in vacuum

1. Optical absorption
2. Electron transport to surface
3. Escape from surface to vacuum (NEA)

Two aspects of emitted electrons in polarized photocathode: density and spins

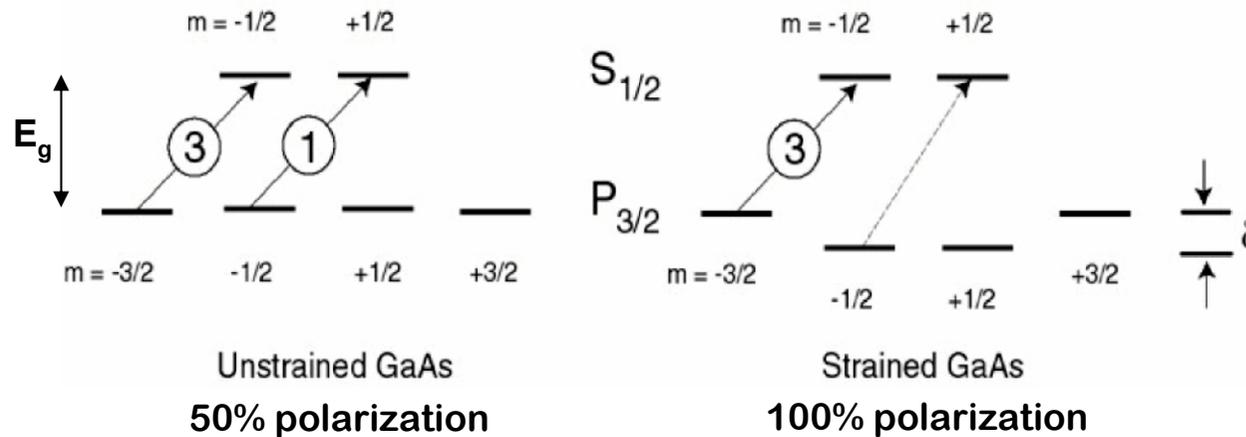


- Improvement:
1. increase QE
  2. increase polarization

# Basics of polarized electron photocathode

## Semiconductor: suitable material for polarized photocathodes

Non-zero transition matrix elements for semiconductors under circular-polarized light illumination



Strained SL : highest polarization (HH-LH splitting further increased due to the quantum confinement by SL)

Initial polarization: 
$$P_0 = (n_{\uparrow} - n_{\downarrow}) / (n_{\uparrow} + n_{\downarrow})$$

# Why Sb-based SL?

## Existing structures in literature

1. InGaAs/AlGaAs (strained well), 70-80%, QE~0.7%
  2. GaAs/GaAsP (strained well), 92%, measured, QE~1%
  3. GaAs/AlInGaAs (strained barrier), 91%
  4. AlInGaAs/GaAsP (strain-balanced), 84%
  5. AlInGaAs/AlGaAs (strained well), 92% with QE~0.85%
- } All HH-LH splittings < 95 meV

## GaAs/GaAs<sub>0.64</sub>P<sub>0.36</sub> SL:

Best overall performance thus far, HH-LH splitting  $\delta \sim 92$  meV

## GaAs<sub>0.85</sub>Sb<sub>0.15</sub>/Al<sub>0.25</sub>GaAsP<sub>0.15</sub> SL:

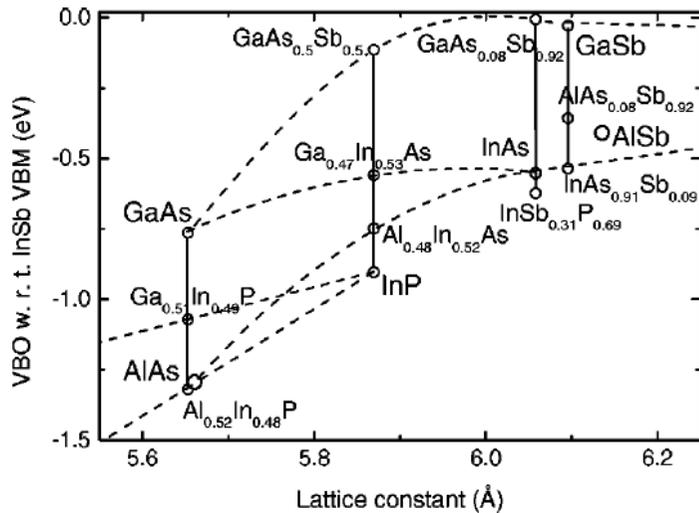
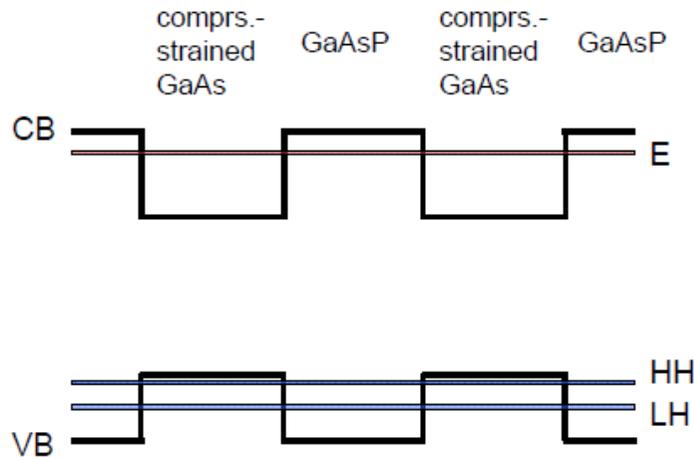
- highest VB offset  $\Rightarrow$  Highest HH-LH splitting:  $\delta > 150$  meV resulting in highest initial polarization and larger tolerance to  $\gamma$
- Dislocation-free SL material since no strain relaxed layer required, boost QE
- No need to grow very thick metamorphic buffer (5-10  $\mu\text{m}$ ), cost-effective

GaAsSb/AlGaAsP SL Photocathode – High Polarization and High QE

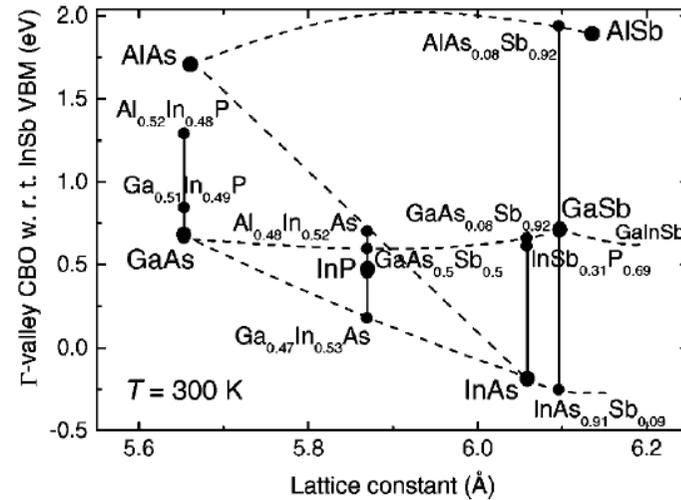
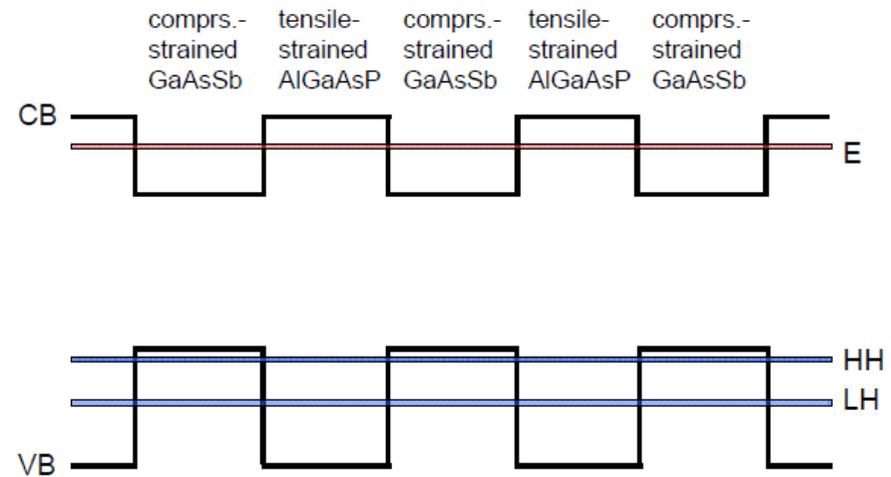


# Very High VB offset in GaAsSb/AlGaAs Heterostructure

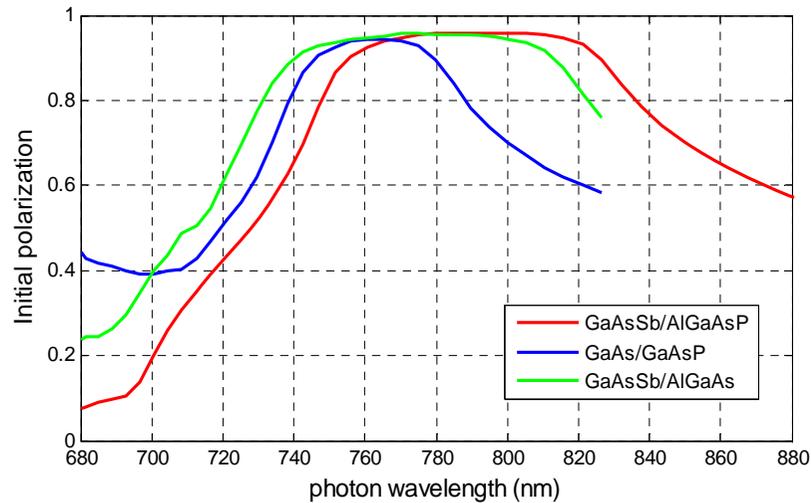
## GaAs/GaAsP SL



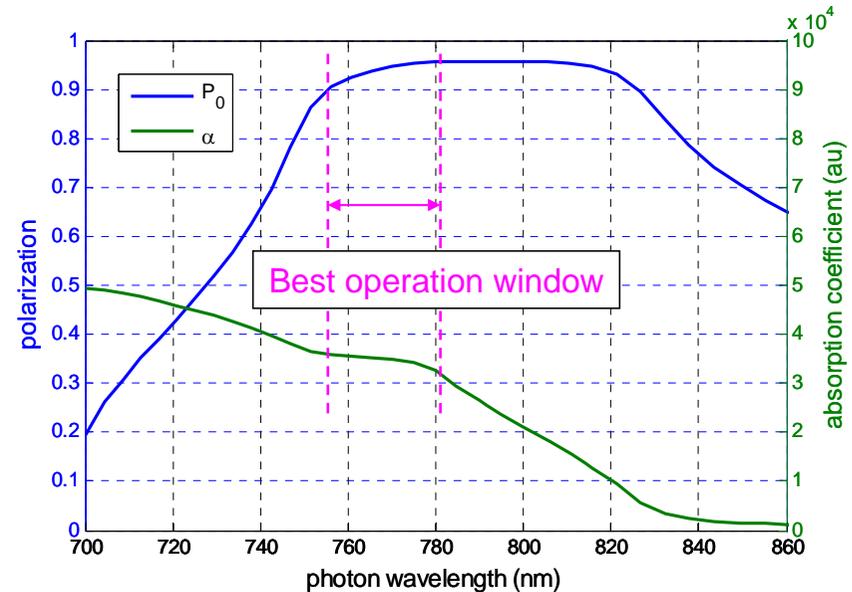
## GaAsSb/AlGaAsP SL



# GaAsSb/AlGaAsP SL: wider high $P_0$ range and larger tolerance to $\gamma$



Comparison of the initial polarization of photocathodes based on GaAs<sub>0.85</sub>Sb<sub>0.15</sub>/ Al<sub>0.25</sub>Ga<sub>0.75</sub>As<sub>0.85</sub>P<sub>0.15</sub> SL, GaAs/GaAs<sub>0.67</sub>P<sub>0.33</sub> SL and GaAs<sub>0.85</sub>Sb<sub>0.15</sub>/ Al<sub>0.4</sub>Ga<sub>0.6</sub>As on GaAs substrate. Line spreading width  $\gamma=10$  meV is used for all three.



Calculated absorption coefficient and initial polarization for GaAs<sub>0.85</sub>Sb<sub>0.15</sub> (6ML) / Al<sub>0.25</sub>Ga<sub>0.75</sub>As<sub>0.85</sub>P<sub>0.15</sub> (14ML) SL on GaAs substrate.

$$\text{Broadening of band, } \gamma : \delta(\omega_m(\vec{k}_{\parallel}, k_z) - \omega) \rightarrow \frac{1}{\pi} \text{Im} \frac{1}{\omega - \omega_m(\vec{k}_{\parallel}, k_z) - i\gamma}$$



# Cooled shutter for As/P/Sb material system

- As and P very volatile -> unwanted P into GaAsSb
- Instant flux shut off of P by cooled shutter -> sharp SL interfaces

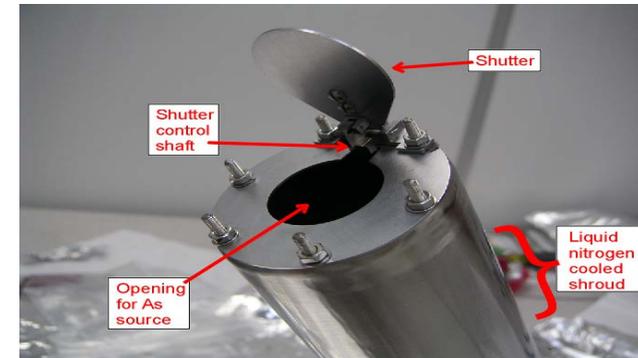
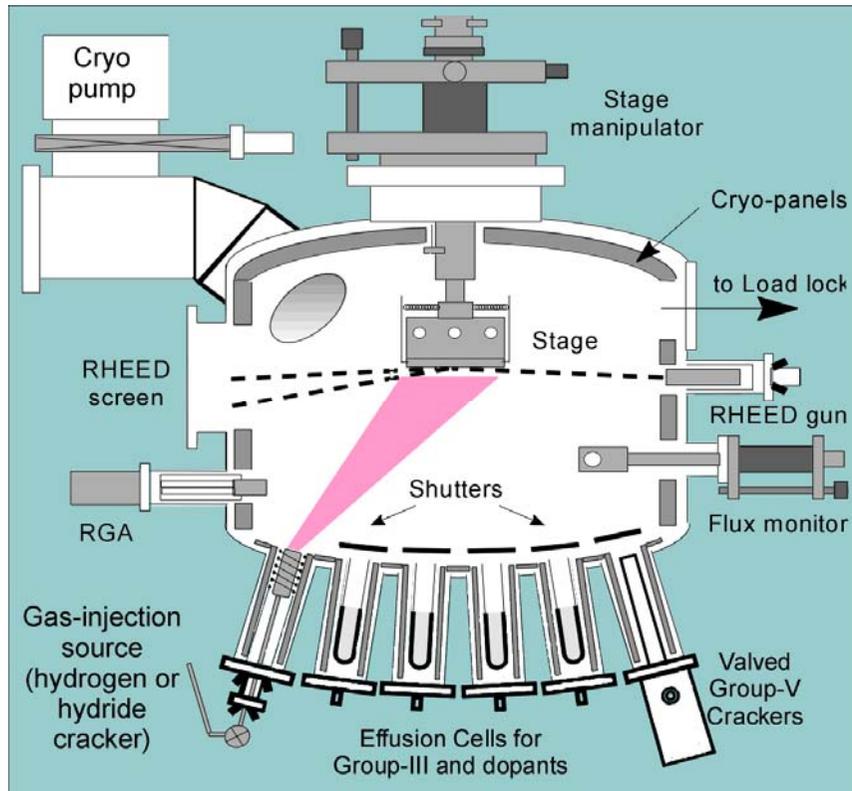
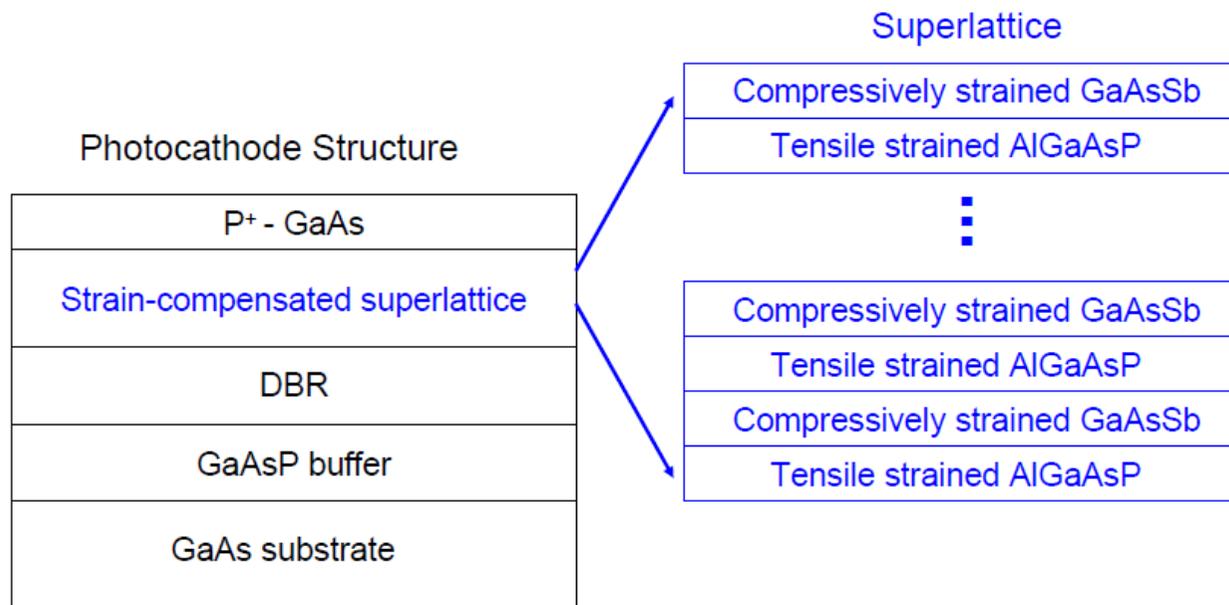


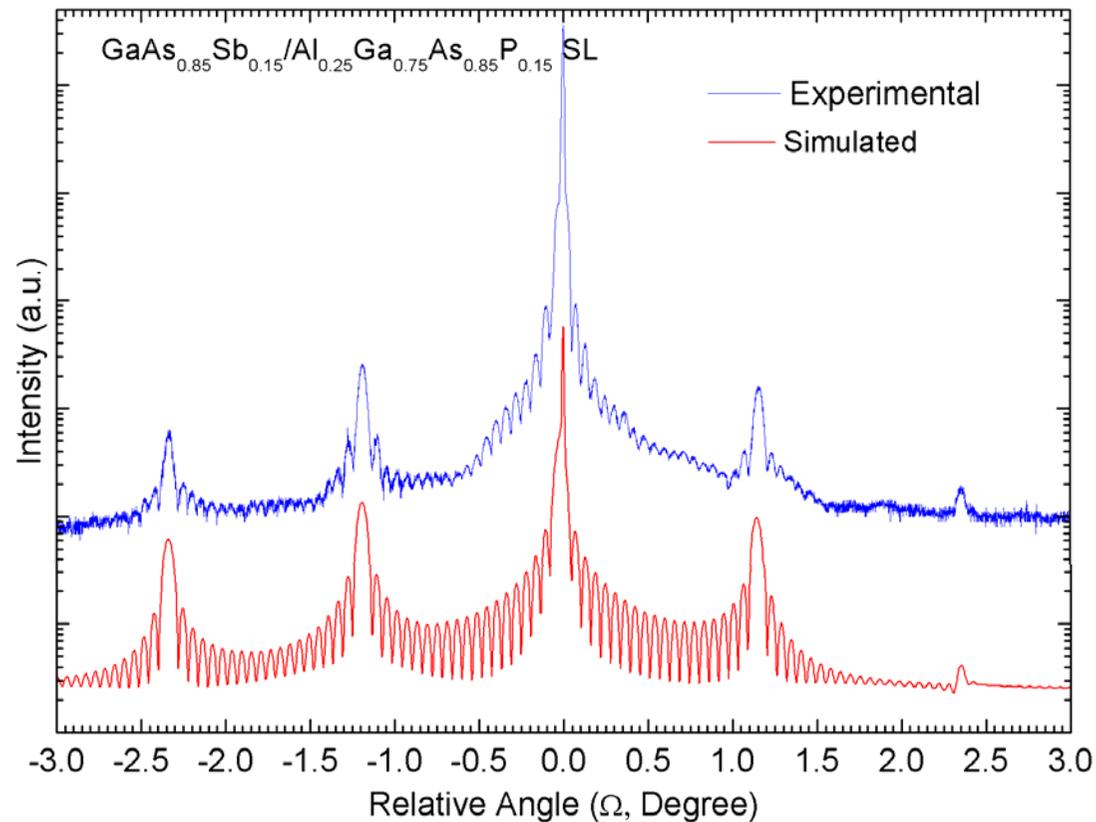
Photo of the output end of the independently cooled shroud/shutter assembly for phosphorus flux abatement. The shutter can change states in a sub-second time scale.

# Key benefits of proposed approaches

- Improved polarization by large HH-LH splitting.
- Significantly improved material quality and thicker SL absorber region boosting QE by fully strain-compensated GaAsSb/AlGaAsP SL.
- An effective InAlP/InGaP DBR structure on a GaAs substrate to enhance QE through more efficient photon absorption.
- Cooled shutter approach to improve interface quality of GaAsSb/AlGaAsP SLs.



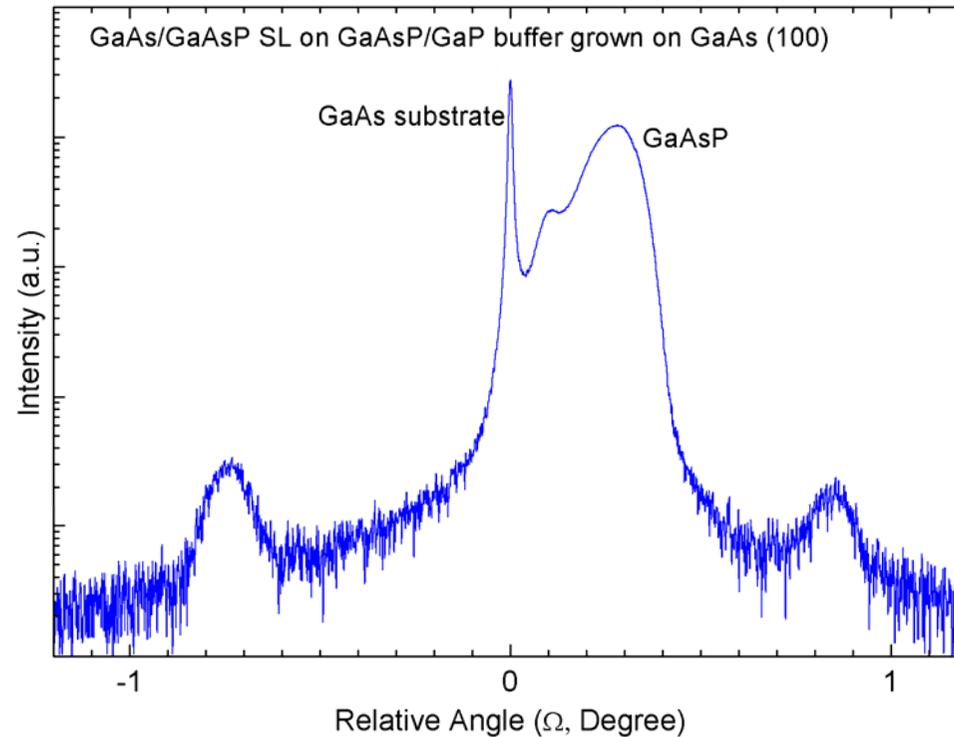
# High-quality GaAsSb/AlGaAsP SL material achieved



Measured and simulated XRD rocking curves for a GaAs<sub>0.85</sub>Sb<sub>0.15</sub>/Al<sub>0.25</sub>Ga<sub>0.75</sub>As<sub>0.85</sub>P<sub>0.15</sub> SL structure grown on GaAs.

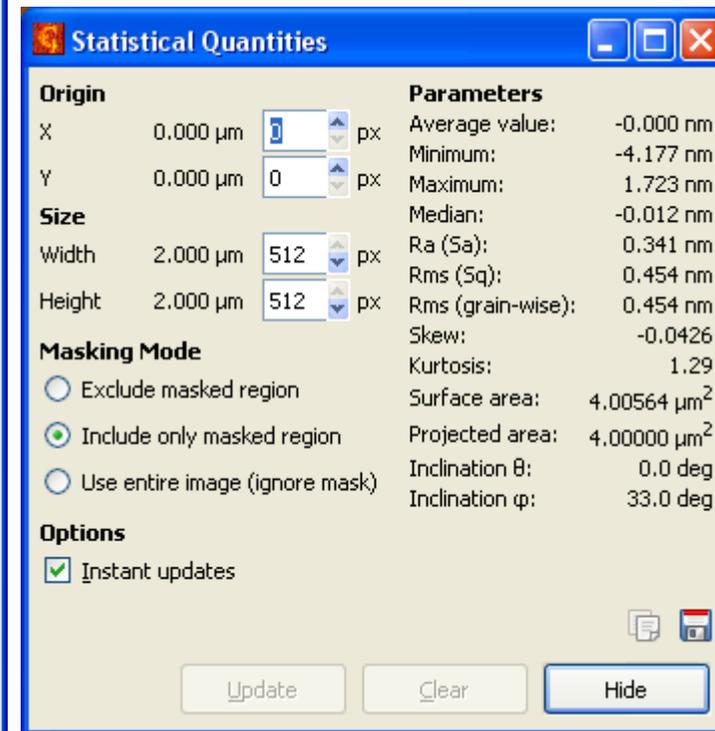
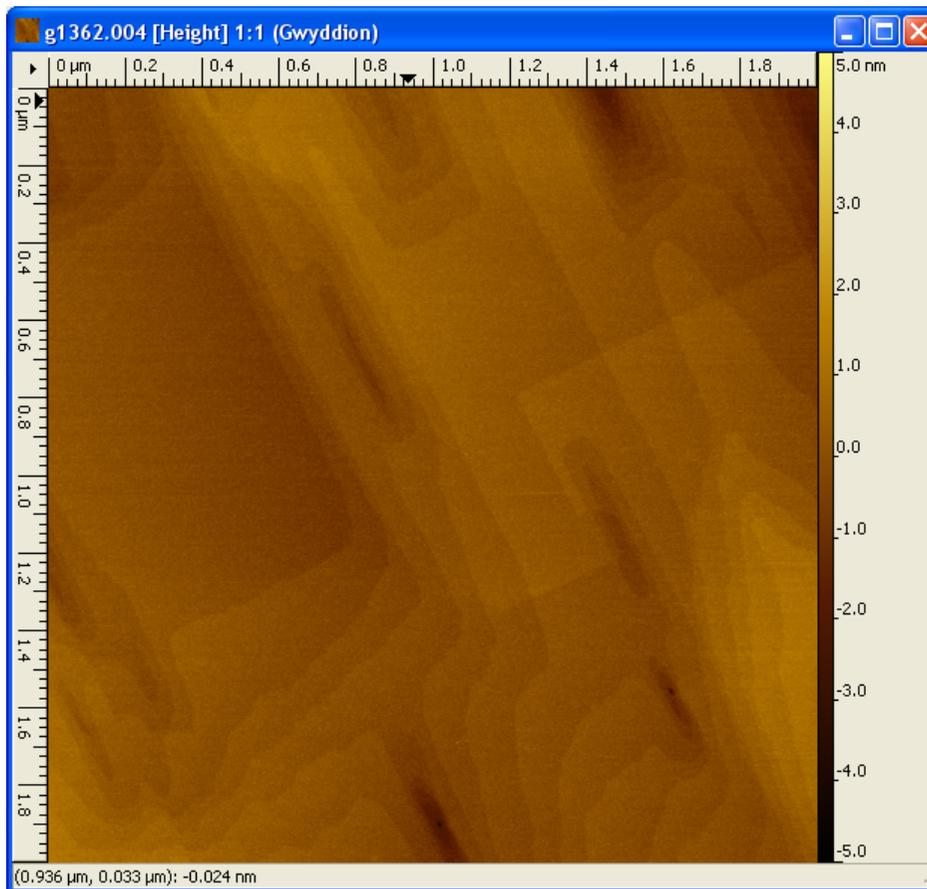
# Recent progress on GaAs/GaAsP photocathodes

- Novel thin (~50nm) GaP buffer instead of thick (~5000nm) graded GaAsP buffer.
- Fast relaxation of GaP on GaAs.
- Direct growth of GaAsP on GaP; no graded GaAsP required.
- Structurally high quality GaAs/GaAsP SL achieved.



High-resolution X-ray diffraction curve for GaAs/GaAsP SL grown on GaP/GaAs.

## AFM picture for GaAs/GaAsP SL grown on GaP/GaAs



# Summary

## Progress

- SL structure design and DBR design completed
- Equipment upgrade completed (P pumping system, dedicated MBE P/Sb system)
- MBE growth of GaAsSb/AlGaAsP SL performed, encouraging initial material result
- Delay due to cryo-shroud leakage; leakage fixed and maintenance completed.

## Next step

- Optimization of MBE growth of GaAsSb/AlGaAsP SLs
- MBE growth and optical testing of DBRs
- MBE growth of GaAsSb/AlGaAsP SL photocathodes
- Device fabrication and testing (JLab)

